

L Number	Hits	Search Text	DB	Time stamp
-	25732	((ozone near8 generator) or (ozone near9 (gas or atmosphere)))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/21 07:22
-	93487	((wafer or semiconductor or substrate) near15 (spin or spinning or rotate or rotates or rotary or rotating or turning or centrifuge or centrifuging))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/21 07:25
-	56612	((spray or sprayer or spraying or jet or nozzle or jetted) near15 (water or liquid or chemicals or acid or solution or solvent)) near15 (wash or washing or clean or cleaning or rinse or rinsing or rinsed))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/21 07:34
-	136	((ozone near8 generator) or (ozone near9 (gas or atmosphere))) and ((wafer or semiconductor or substrate) near15 (spin or spinning or rotate or rotates or rotary or rotating or turning or centrifuge or centrifuging)) and (((spray or sprayer or spraying or jet or nozzle or jetted) near15 (water or liquid or chemicals or acid or solution or solvent)) near15 (wash or washing or clean or cleaning or rinse or rinsing or rinsed))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/21 07:29
-	56885	((spray or sprayer or spraying or jet or nozzle or jetted) near15 (water or liquid or chemicals or acid or solution or solvent)) near15 (wash or washing or clean or cleaning or rinse or rinsing or rinsed or decontamination or decontaminate or decontaminating))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/21 07:33
-	136	((ozone near8 generator) or (ozone near9 (gas or atmosphere))) and ((wafer or semiconductor or substrate) near15 (spin or spinning or rotate or rotates or rotary or rotating or turning or centrifuge or centrifuging)) and (((spray or sprayer or spraying or jet or nozzle or jetted) near15 (water or liquid or chemicals or acid or solution or solvent)) near15 (wash or washing or clean or cleaning or rinse or rinsing or rinsed or decontamination or decontaminate or decontaminating))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/21 07:35
-	10333	((spray or sprayer or spraying or jet or nozzle or jetted) near15 (water or liquid or chemicals or acid or solution or solvent)) near15 (wash or washing or clean or cleaning or rinse or rinsing or rinsed))	USOCR	2004/04/21 07:35
-	13	"5896875" and ozone	USPAT	2004/04/21 08:13
-	16	"5896875" and (hot or heat or heater or heated)	USPAT	2004/04/21 09:10
-	7	(ozone near5 generator) same (sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating) same (wafer or semiconductor or substrate) same (wash or washing or clean or cleaning or rinse or rinsing or rinsed)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/21 09:14
-	169	(ozone near5 generator) and (sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating) and (wafer or semiconductor or substrate) and (wash or washing or clean or cleaning or rinse or rinsing or rinsed)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/21 09:53

-	7	"5518542" and ozone	USPAT	2004/04/21 10:50
-	27	(ozone near5 generator) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating) near27 (nozzle or jet or spray or sprayer)) and (wafer or semiconductor or substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/21 10:26
-	0	(ozone near5 generator) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating) near27 (nozzle or jet or spray or sprayer)) and (wafer or semiconductor or substrate)	USOCR	2004/04/21 10:09
-	0	(ozone near5 generator) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating) near27 (jig or carrier or holder or chuck)) and (nozzle or jet or spray or sprayer) and (wafer or semiconductor or substrate)	USOCR	2004/04/21 10:10
-	5	(ozone near5 generator) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating) near27 (jig or carrier or holder or chuck)) and (nozzle or jet or spray or sprayer) and (wafer or semiconductor or substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 10:19
-	5	(ozone near20 generator) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating) near27 (jig or carrier or holder or chuck)) and (nozzle or jet or spray or sprayer) and (wafer or semiconductor or substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 10:20
-	8	"5964954" and ozone	USPAT	2004/04/21 10:24
-	8	(ozone near25 generator) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating) near27 (carrier or chuck or rotor or holder)) and (wafer or semiconductor or substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 10:28
-	8	(ozone near25 generator) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating or vibrated or shaken or oscillated or vibrating) near27 (carrier or chuck or rotor or holder)) and (wafer or semiconductor or substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 10:28
-	14	(ozone near25 generator) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating or vibrated or shaken or oscillated or vibrating) same (carrier or chuck or rotor or holder)) and (wafer or semiconductor or substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 11:12
-	240	(ozone near25 generator) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating or vibrated or shaken or oscillated or vibrating)) and (wafer or semiconductor or substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/21 10:33
-	1	(ozone near25 generator) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating or vibrated or shaken or oscillated or vibrating) same (carrier or chuck or rotor or holder)) and (wafer or semiconductor or substrate)	USOCR	2004/04/21 10:32

-	189	(ozone near25 generator) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating or vibrated or shaken or oscillated or vibrating)) and (wafer or semiconductor or substrate) and (wash or washing or clean or cleaning or rinse or rinsing or rinsed)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/28 07:36
-	0	"6615277" and ozone	USPAT	2004/04/21 10:50
-	4	"6165277" and ozone	USPAT	2004/04/21 11:12
-	218	((carrier or chuck or rotor or holder) near10 (sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating or vibrated or shaken or oscillated or vibrating)) same (wafer or substrate or semiconductor) near15 ((wash or washing or clean or cleaning or rinse or rinsing or rinsed or decontaminated or decontamination or decontaminating))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/21 12:49
-	49	29/\$.CCLS. AND DISHWASHER	USPAT	2004/04/23 06:12
-	19	"6240933"	USPAT	2004/04/28 06:25
-	5	"6240933" and (sonic or megasonic or ultrasonic or vibrate or vibration)	USPAT	2004/04/28 06:48
-	0	"6591845" and (sonic or megasonic or ultrasonic or vibrate or vibration)	USPAT	2004/04/28 06:49
-	1	"6591845"	USPAT	2004/04/28 06:50
-	8926	(ozone near15 generator) or (ozone near15 (gas or atmosphere)) and (wafer or semiconductor or substrate) and (spray or sprayer or nozzle or jet) and (spin or spinning or rotor or rotate or rotary or turn or turning) and (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontamination))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/28 07:00
-	8926	((ozone near15 generator) or (ozone near15 (gas or atmosphere)) and (wafer or semiconductor or substrate) and (spray or sprayer or nozzle or jet) and (spin or spinning or rotor or rotate or rotary or turn or turning) and (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontamination))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/28 07:01
-	8291	((ozone near15 generator) or (ozone near15 (gas or atmosphere)) and (((wafer or semiconductor or substrate) and (spray or sprayer or nozzle or jet) near25 (spin or spinning or rotor or rotate or rotary or turn or turning)) same (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontamination)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/28 07:02
-	8266	((ozone near15 generator) or (ozone near15 (gas or atmosphere)) and (((wafer or semiconductor or substrate) and (spray or sprayer or nozzle or jet) near25 (spin or spinning or rotor or rotate or rotary or turn or turning)) near25 (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontamination)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/28 07:02

-	45	((ozone near15 generator) or (ozone near15 (gas or atmosphere))) and (((wafer or semiconductor or substrate) and (spray or sprayer or nozzle or jet) near25 (spin or spinning or rotor or rotate or rotary or turn or turning)) near25 (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontamination)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/28 07:02
-	77	((ozone near15 generator) or (ozone near15 (gas or atmosphere))) and (((wafer or semiconductor or substrate) and (spray or sprayer or nozzle or jet) near25 (spin or spinning or rotor or rotate or rotary or turn or turning)) same (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or decontamination)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/28 07:13
-	553	((wafer or semiconductor or substrate) near15 (batch or boat or carrier)) and ((wafer or semiconductor or substrate) near15 (single or individual))) and ((heat or heater or hot or heated or heating) or (sonic or ultrasonic or megasonic or hertz or mhz or vibration or vibrate or socillator or oscillation or oscillate) or ozone) and 134/\$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/28 07:16
-	41	(ozone near15 (gas or atmosphere or generator or supply)) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating or vibrated or shaken or shook or oscillated or vibrating or vibration)) same ((wafer or semiconductor or substrate) near18 (spin or spinning or rotate or rotary or rotor or rotary or centrifuge or centrifuging or rotates or spinner or spins)) same (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or rinsed)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/28 07:50
-	0	(ozone near15 (gas or atmosphere or generator or supply)) and ((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating or vibrated or shaken or shook or oscillated or vibrating or vibration)) same ((wafer or semiconductor or substrate) near18 (spin or spinning or rotate or rotary or rotor or rotary or centrifuge or centrifuging or rotates or spinner or spins)) same (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or rinsed)	USOCR	2004/04/28 09:01
-	9	((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating or vibrated or shaken or shook or oscillated or vibrating or vibration)) same ((wafer or semiconductor or substrate) near18 (spin or spinning or rotate or rotary or rotor or rotary or centrifuge or centrifuging or rotates or spinner or spins)) same (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or rinsed)	USOCR	2004/04/28 09:01

-	664	((sonic or ultrasonic or megasonic or vibrator or vibration or oscillation or oscillator or oscillating or vibrated or shaken or shook or oscillated or vibrating or vibration)) same ((wafer or semiconductor or substrate) near18 (spin or spinning or rotate or rotary or rotor or rotary or centrifuge or centrifuging or rotates or spinner or spins)) same (wash or washing or clean or cleaning or rinse or rinsing or decontaminate or decontamination or rinsed)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/28 11:22
-	5	"human body" near15 (clean or wash or decontaminate) near15 (method or precess)	USPAT	2004/04/28 11:24
-	10	"human body" near15 (clean or wash or decontaminate) near15 (method or process)	USPAT	2004/04/29 06:55
-	2	"6325081" and (heat or heater heating or hot)	USPAT	2004/04/29 06:57
-	0	"6199567" and (heat or heater heating or hot)	USPAT	2004/04/29 07:14
-	6611	((wafer or semiconductor or substrate) same ((reservoir or supply) near5 (heated or heat or heater)))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/29 07:16
-	57	((wafer or semiconductor or substrate) same ((reservoir or supply) near5 (heated or heat or heater))) same (sonic or ultrasonic or megasonic or vibrated or oscillator or oscillating)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/29 07:22
-	488	((wafer or semiconductor or substrate) same (wash or washing or clean or cleaning or rinse or rinsing or decontamination or decontaminate)) and ((reservoir or supply) near5 (heated or heat or heater)) and (sonic or ultrasonic or megasonic or vibrated or oscillator or oscillating)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/29 07:34
-	67	((wafer or semiconductor or substrate) same (wash or washing or clean or cleaning or rinse or rinsing or decontamination or decontaminate)) and ((reservoir or supply) near5 (heated or heat or heater)) and (sonic or ultrasonic or megasonic or vibrated or oscillator or oscillating) and (ozone near10 (gas or atmosphere))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/29 07:58
-	538	((wafer or semiconductor or substrate) near15 (batch or boat or carrier)) and ((wafer or semiconductor or substrate) near15 (single or individual))) and ((heat or heater or hot or heated or heating) or (sonic or ultrasonic or megasonic or hertz or MHZ or vibration or vibrate or oscillator or oscillation or oscillate) or ozone)	JPO; DERWENT	2004/04/29 08:15
-	2145	((wafer or semiconductor or substrate) near15 (washing or wash or rinsed or rinsing or decontaminate or decontamination or decontaminating)) and ((holder or support or chuck or jig) near15 (sonic or ultrasonic or megasonic or oscillator or oscillate or oscillation or vibrate or vibration or vibrating))	JPO; DERWENT	2004/04/29 08:20
-	1567	((wafer or semiconductor or substrate) near15 (washing or wash or rinsed or rinsing or decontaminate or decontamination or decontaminating)) same ((holder or support or chuck or jig) near15 (sonic or ultrasonic or megasonic or oscillator or oscillate or oscillation or vibrate or vibration or vibrating))	JPO; DERWENT	2004/04/29 08:20

-	701	((wafer or semiconductor or substrate) near15 (washing or wash or rinsed or rinsing or decontaminate or decontamination or decontaminating)) same ((holder or support or chuck or jig) neat15 (sonic or ultrasonic or megasonic or oscillator or oscillate or oscillation or vibrate or vibration or vibrating))	JPO	2004/04/29 08:23
-	33	((wafer or semiconductor or substrate) near15 (washing or wash or rinsed or rinsing or decontaminate or decontamination or decontaminating)) and ((holder or support or chuck or jig) near15 (sonic or ultrasonic or megasonic or oscillator or oscillate or oscillation or vibrate or vibration or vibrating)) and ozone	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/29 08:24
-	413	((wafer or semiconductor or substrate) near15 (washing or wash or rinsed or rinsing or decontaminate or decontamination or decontaminating)) and ((holder or support or chuck or jig) near15 (sonic or ultrasonic or megasonic or oscillator or oscillate or oscillation or vibrate or vibration or vibrating))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/29 08:31
-	416	((wafer or semiconductor or substrate) near15 (washing or wash or rinsed or rinsing or decontaminate or decontamination or decontaminating)) and ((holder or support or chuck or jig) near15 (sonic or ultrasonic or megasonic or oscillator or oscillate or oscillation or vibrate or vibration or vibrating or vibrator))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/29 08:31
-	21	((wafer or semiconductor or substrate) near15 (washing or wash or rinsed or rinsing or decontaminate or decontamination or decontaminating)) and ((holder or support or chuck or jig) near15 (vibrator))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/29 08:34
-	26	((wafer or semiconductor or substrate) near15 (washing or wash or rinsed or rinsing or decontaminate or decontamination or decontaminating)) and ((holder or support or chuck or jig) near15 (shook or shake or shaken or shaken))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/29 08:41
-	696	((wafer or semiconductor or substrate) near15 (washing or wash or rinsed or rinsing or decontaminate or decontamination or decontaminating)) and (ozone near10 (gas or atmosphere or generator))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/29 09:05
-	3	((wafer or semiconductor or substrate) near15 (washing or wash or rinsed or rinsing or decontaminate or decontamination or decontaminating)) and (spray or sprayer or jet or nozzle or spraying) and ((rotor or turntable or rotary or rotating or rotate or rotates or chuck or holder or support) near10 (sonic or ultrasonic or megasonic or oscillator or oscillating or oscillation or vibrator or vibrating or vibration))	USOCR	2004/04/29 09:09

-	357	((wafer or semiconductor or substrate) near15 (washing or wash or rinsed or rinsing or decontaminate or decontamination or decontaminating)) and (spray or sprayer or jet or nozzle or spraying) and ((rotor or turntable or rotary or rotating or rotate or rotates or chuck or holder or support) near10 (sonic or ultrasonic or megasonic or oscillator or oscillating or oscillation or vibrator or vibrating or vibration))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/29 09:16
-	410	((wafer or semiconductor or substrate) near15 (washing or wash or rinsed or rinsing or decontaminate or decontamination or decontaminating)) and (spray or sprayer or jet or nozzle or spraying) and ((spin or spinner or spinning or centrifuge or centrifuging or rotor or turntable or rotary or rotating or rotate or rotates or chuck or holder or support) near10 (sonic or ultrasonic or megasonic or oscillator or oscillating or oscillation or vibrator or vibrating or vibration))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/04/29 09:18